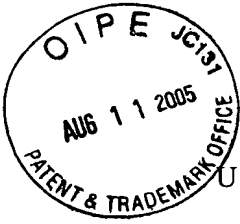


IFW



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

U.S. Serial No. 10/733,067


Applicant: Ji Myong LEE

Title: "Apparatus and Methods of  
Chemical Mechanical Polishing"

Filed: December 11, 2003

Examiner: Thomas, Toniae M.

Docket No.: 20063/OF03P193

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RESPONSE TO THE OFFICE ACTION DATED JULY 7, 2005

Dear Sir:

Please enter the following amendments and consider the following remarks.

**The Status of the Claims** is reflected in the listing of claims that begins on page 2 of this paper.

**Remarks** begin on page 3 of this paper.